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(12) **United States Design Patent** (10) **Patent No.:** **US D1,089,131 S**
Kang (45) **Date of Patent:** **** Aug. 19, 2025**

(54) **INSPECTION EQUIPMENT CONTROL
DEVICE**

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(**) Term: **15 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (15) Cl.** **13-03**

(52) **U.S. Cl.**
USPC **D13/162; D13/184; D14/314**

(58) **Field of Classification Search**

USPC D13/101, 103, 107, 110, 112, 114, 119,
D13/122, 123, 133, 153, 154, 155, 156,
D13/157, 160, 182, 184, 199; D14/300,
D14/308, 439, 440, 314; D24/107, 158,
D24/160

CPC G05B 2219/35001; G05B 2219/37351;
H04N 7/183; G06T 7/0002; G06T
2207/10016; G06T 11/00; G06V 40/172;
B01L 3/502715

See application file for complete search history.

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(57) **CLAIM**

The ornamental design for an inspection equipment control device as shown and described.

DESCRIPTION

FIG. 1 is a perspective view of an inspection equipment control device showing my new design;

FIG. 2 is a front view thereof;

FIG. 3 is a rear view thereof;

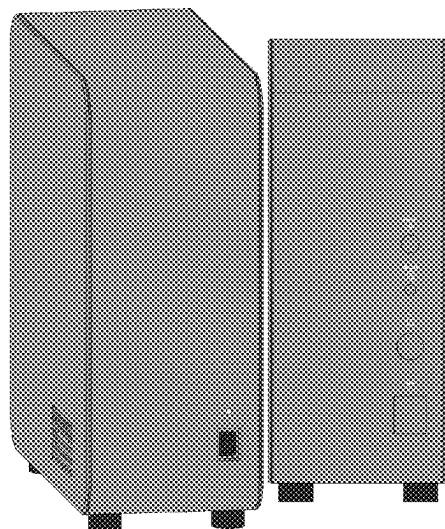
FIG. 4 is a left side view thereof;

FIG. 5 is a right side view thereof;

FIG. 6 is a top view thereof; and,

FIG. 7 is a bottom view thereof.

1 Claim, 7 Drawing Sheets



(56)

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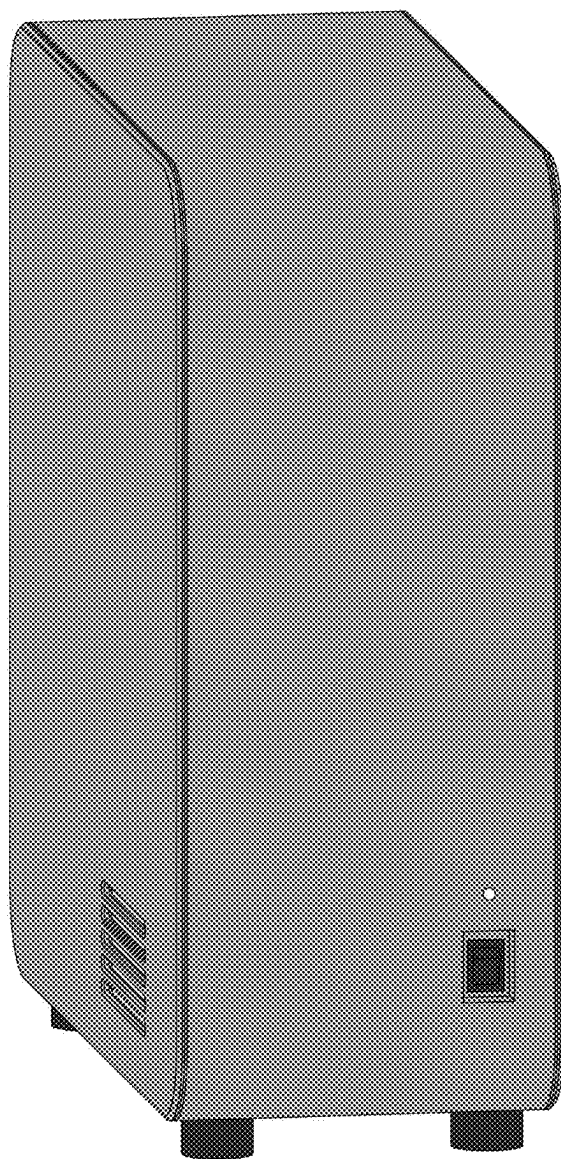


FIG. 1

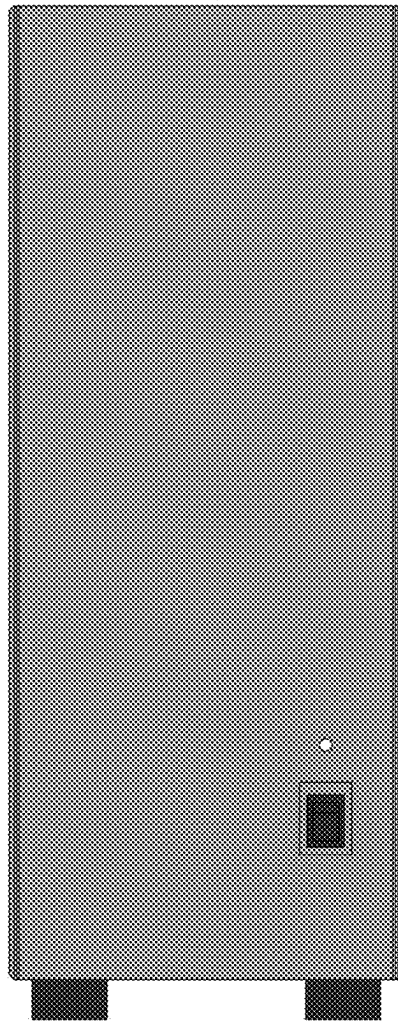


FIG. 2

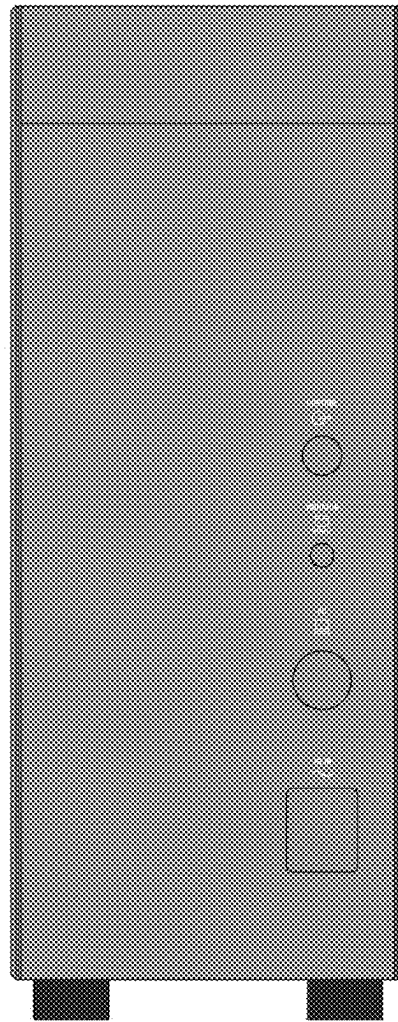


FIG. 3

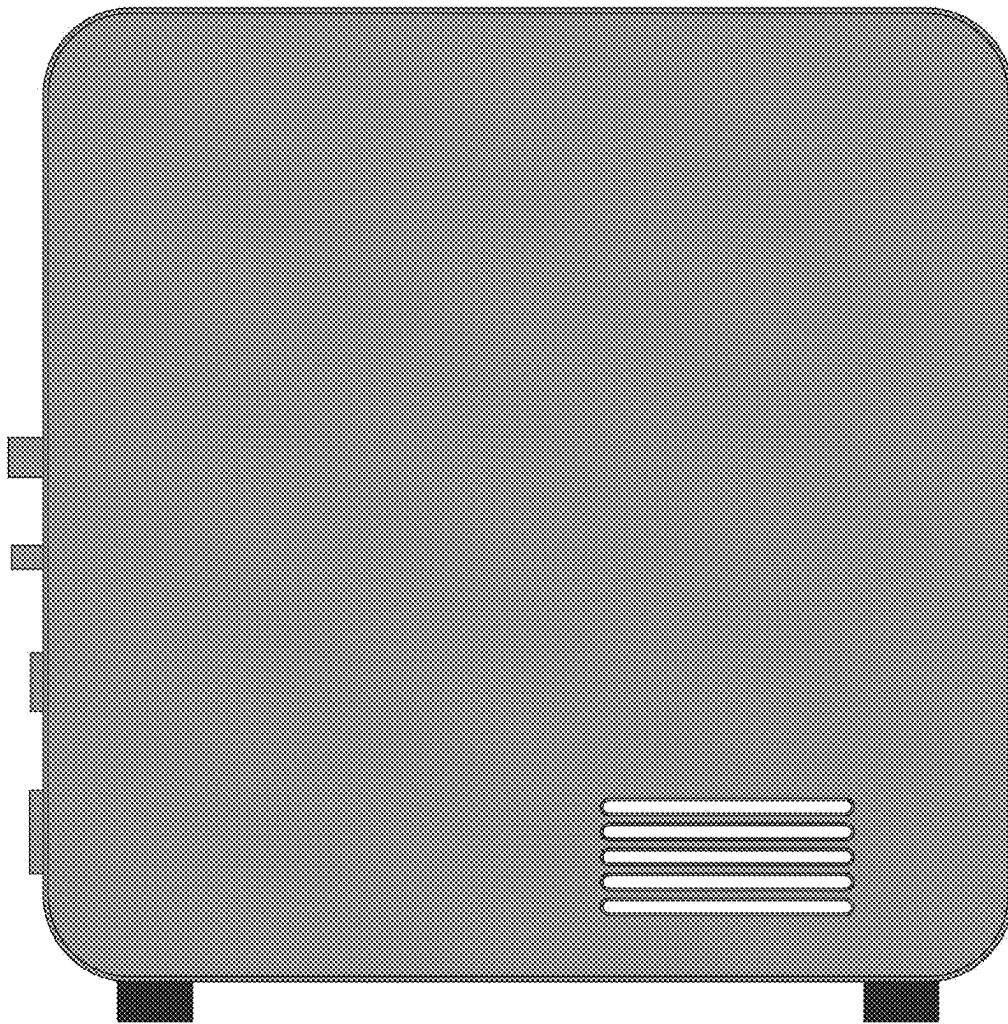


FIG. 4

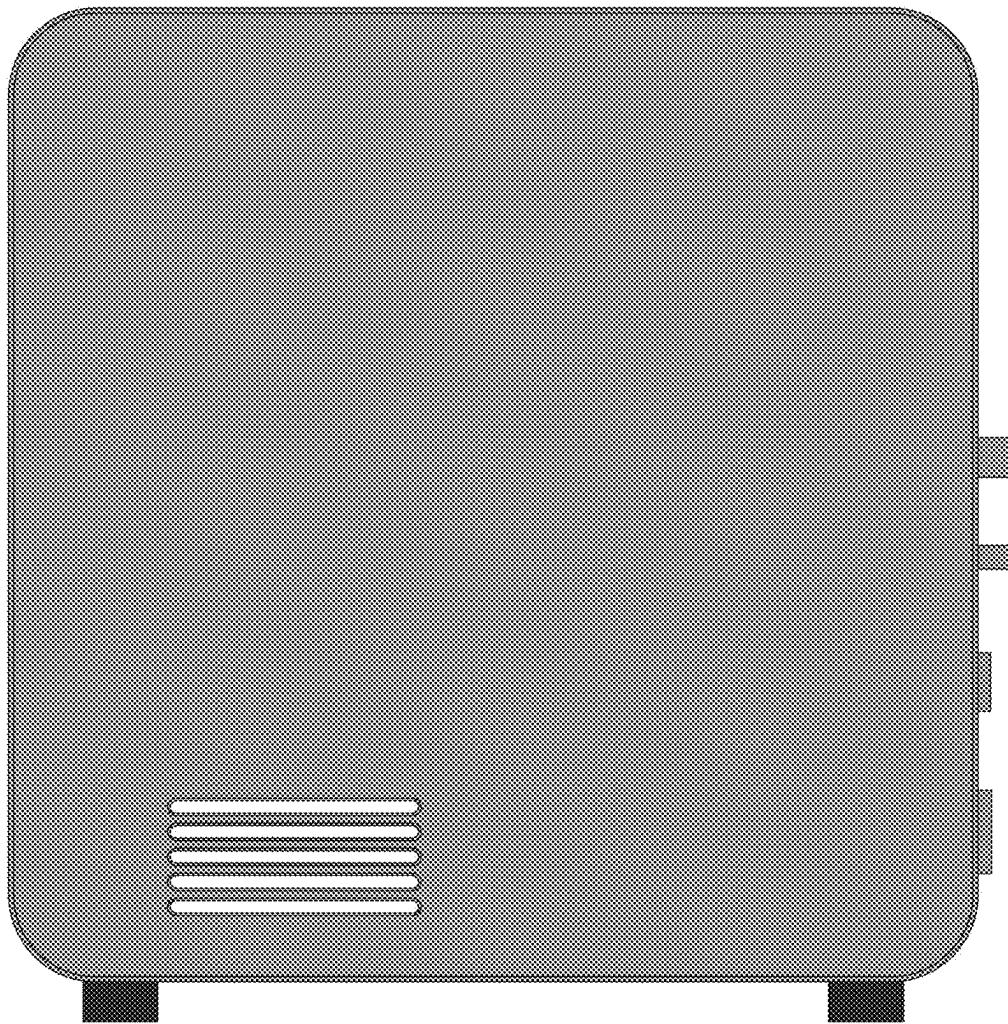


FIG. 5

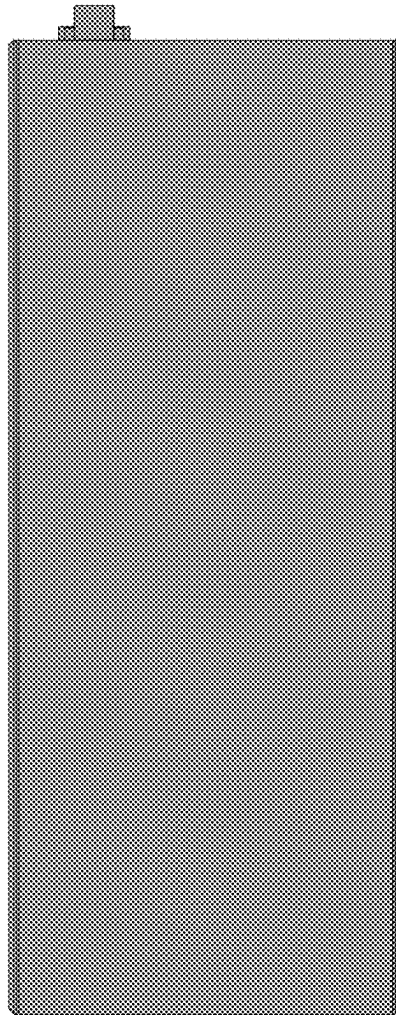


FIG. 6

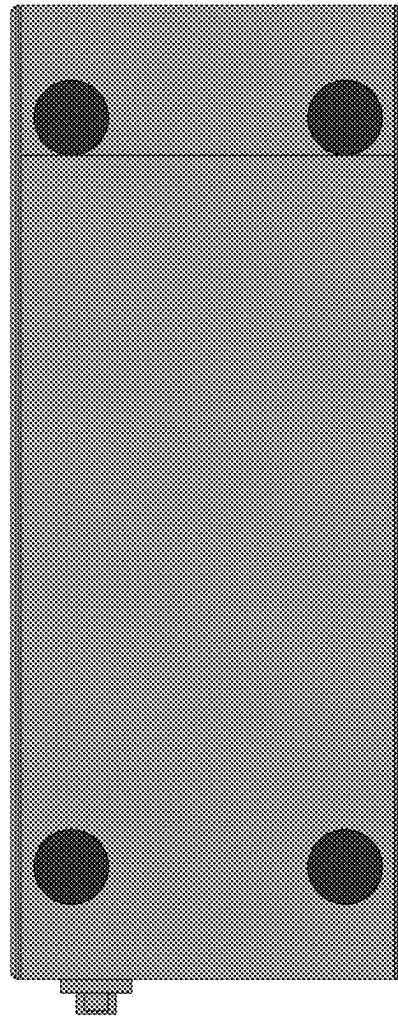


FIG. 7